IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Chandra V. Mouli § Group Art Unit:

2812 FECHALLES CELLER 2300

Serial No.: 09/379,092

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August 23, 1999 Filed:

§ Examiner:

R. Pompey

For:

FORMING SIDEWALL OXIDE

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LAYERS FOR TRENCH

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ISOLATION

§ Atty. Dkt. No.: MICT-0042-US

Box AF Commissioner for Patents Washington DC 20231

REPLY TO FINAL REJECTION

Sir:

In response to the office action mailed June 28, 2001, please consider the following remarks.

Remarks

Claims 1 and 33 stand rejected under §102 based on the reference to Hong. (The taking of official notice was only with respect to the §103 rejection of the dependent claims.)

Reconsideration of the §102 rejection of claims 1 and 33 is requested. Claim 1 calls for implanting impurities which enhance the oxidation of said structure beyond that which would be expected from crystallographic damage effects. The final rejection states that "Hong is silent on what produces the oxidation enhancement by implanting dopant species into the substrate. Therefore, it is not disclosed whether it is crystallographic damage . . . " In view of this statement, it is clear that the §102 rejection of claim 1 is not appropriate.

> Date of Deposit:_ I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, Washington DC 20231.

Lisa O'Sullivan